

(19)
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(A)

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(21)	10-2002-0009071	
(22)	2002 02 20	
(71)	3 416	
(72)	1 112-508	
	108 303	
(74)		
:		
(54)		

가

2

1

2

3a 3e 2

4 1

5 2

100 : 101 :
 102 : 104, 300 :
 106 : 108 :
 110 : 112 :
 114 : 116, 118 :
 120, 122 : / 125 :
 126 : 128 :
 130, 200 : 132 :
 134 : 136 :
 138 : 140 :

(active matrix organic light emitting device; AMOLED)
 (contrast)
 (electronic display device)
 가
 가
 가
 가
 (emissive
 (non-emissi
 (cathode ray t
 (light emitting diode; LED)
 (electrochemical display;
 (CRT)
 가
 가
 (flat panel)
 가

가 .

가 가

(cathode) (anode) (electron) (hole)
(exciton) 가

100 200V 가 ,
5 20V (high contrast)

1

1 (10) (blocking layer
) (12) (12)

(12) (14), (16), (18), (20) /
(26, 28) (30)가

(30) (10) (32) (32) (34)
/ (26, 28) (28) (36)
(indium-tin-oxide) (indium-zinc-oxide)
(36) (50) (anode)

(36) (32) (36) (42) (4
(40) (50) (42) (cathode) (44)

(30)가 (10) (50) (30)가 (10) (30)
(30), 가
(off) (50) (black) (46) 가 가

가 60% 가 50%

가

Figure 1. Schematic diagram of the structure of the CrOx/NiOx/FeOx/ITO/IZO heterostructure. The structure consists of a substrate (3a) with a 3e layer (2) on top. The heterostructure is composed of layers of CrOx, NiOx, FeOx, ITO, and IZO. The layers are labeled with their respective crystallographic planes: (104) for CrOx, (102) for NiOx, (106) for FeOx, (108), (110), (112), (114), (116, 118) for ITO, and (108), (110), (112), (114), (116, 118) for IZO. The thickness of the ITO layer is indicated as 1 μm. The layers are separated by a thin layer of (104) and (106) planes. The structure is shown in a cross-sectional view.

Exemplar	Substrate	Deposition Method	Deposition Conditions	Crystallinity	Thickness	Composition	Properties
3a	CrOx	(102)	1000	(101)	500	(100)	Cr, Ni
3b	(plasma-enhanced chemical vapor deposition; PECVD)	(106)	2000	(104)	(100)	(101)	CrOx, NiOx
3c	(low pressure CVD; LPCVD)	(107)	440	450mJ/cm ²	(106)	(107)	PECVD
3d	(114)	(116, 118)	(114)	(116, 118)	(114)	(114)	(114)
3e	(120, 122)	(126)	(122)	(128)	(126)	(126)	(126)

, (134) (hole transfer layer; HTL)(), (136),
 (electron transfer layer; ETL)(),
 (140) (138) .

4 1 .

4 , (g1), (d1) (Vdd1)
 (TFT), ()
 가 (Vdd1) (Vdd) 가

00) 40% , (200) (2
 (TFT) (g1, d1, Vdd1) (300) ,
 (200) ,

5 2 .

5 , (g1, g2), (d1) (Vdd1)
 (TFT), ()
 가 .

20% , (200) (TFT) (g1, g2, d1, Vdd1)
 (200) (300) , (200) ,

50% 가 .

(57)

1.

2.

1 , .

3.

2 , .

4.

1 , .

5.

4 , / , / / .

6.

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;

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;

;

7.

6 , .

8.

6 , 1μm .

9.

;

;

;

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;

;

;

;

10.

9 , , .

11.

9 , :

;

;

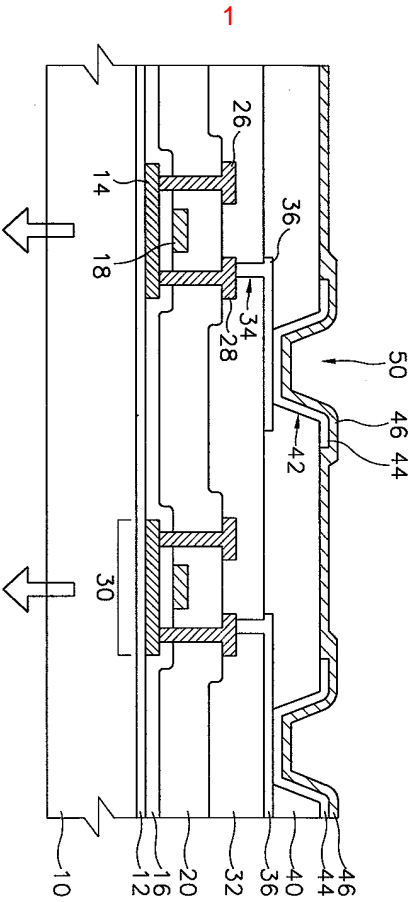
1 μm

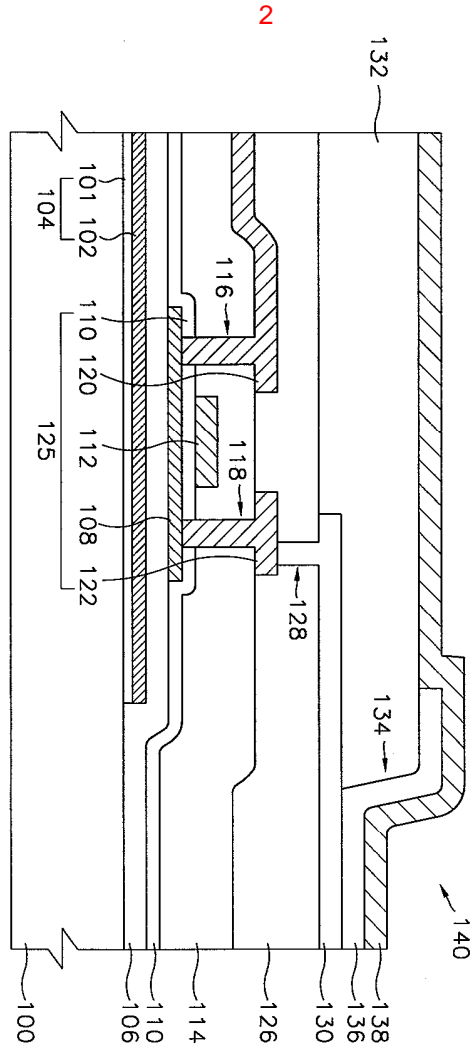
12.

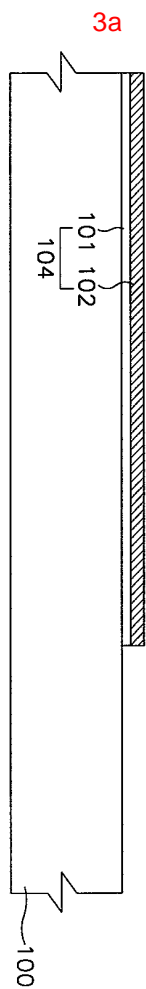
9 ,

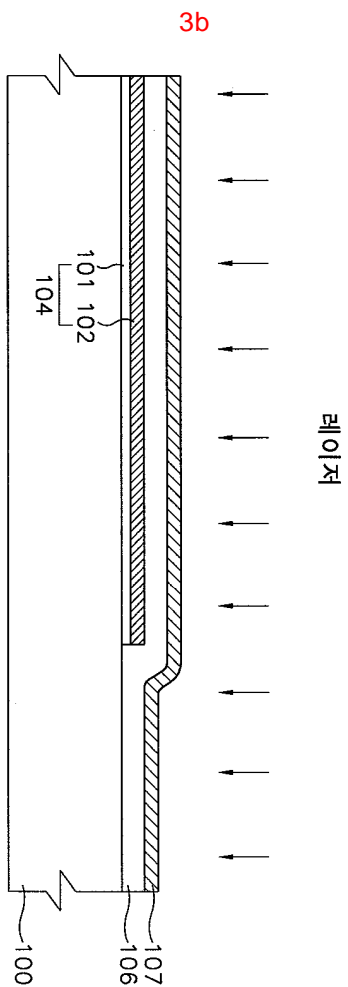
13.

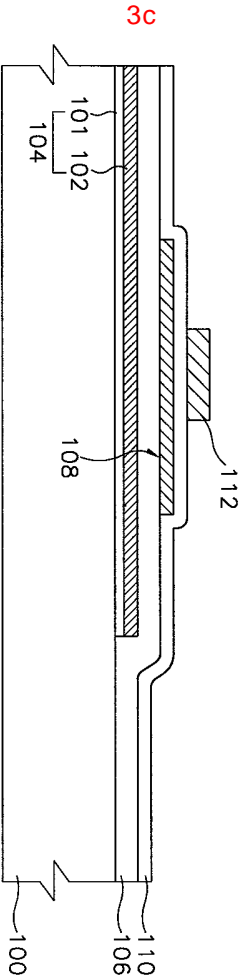
9 , / , / /

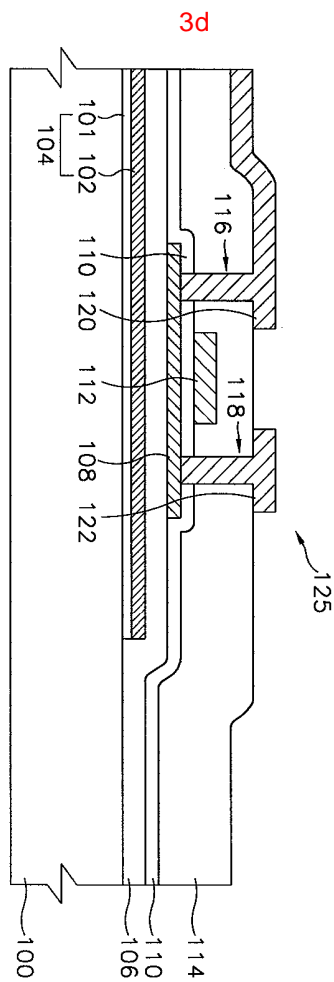


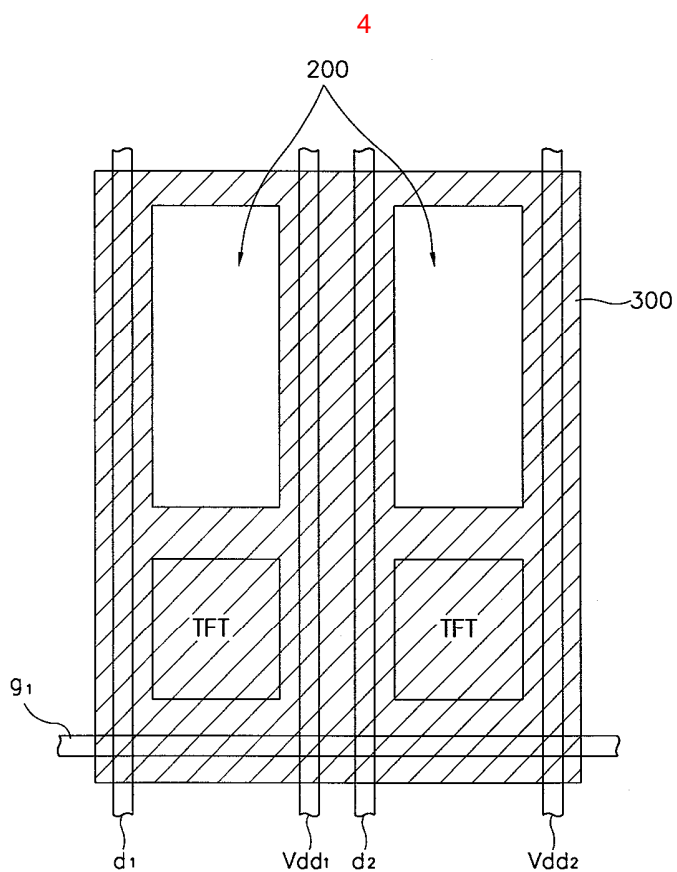
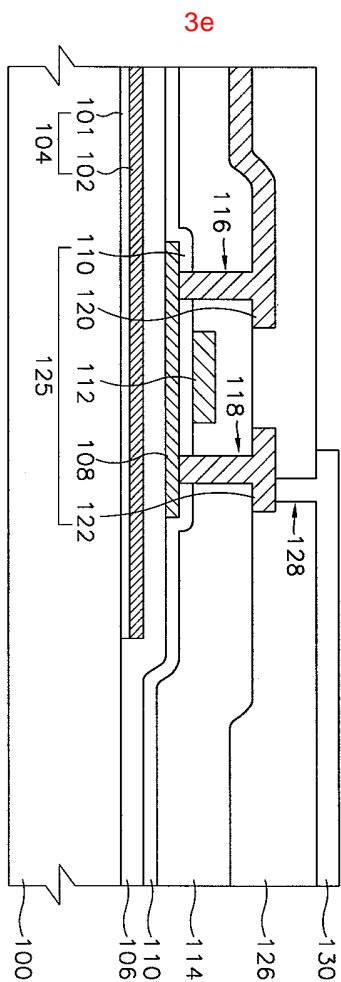


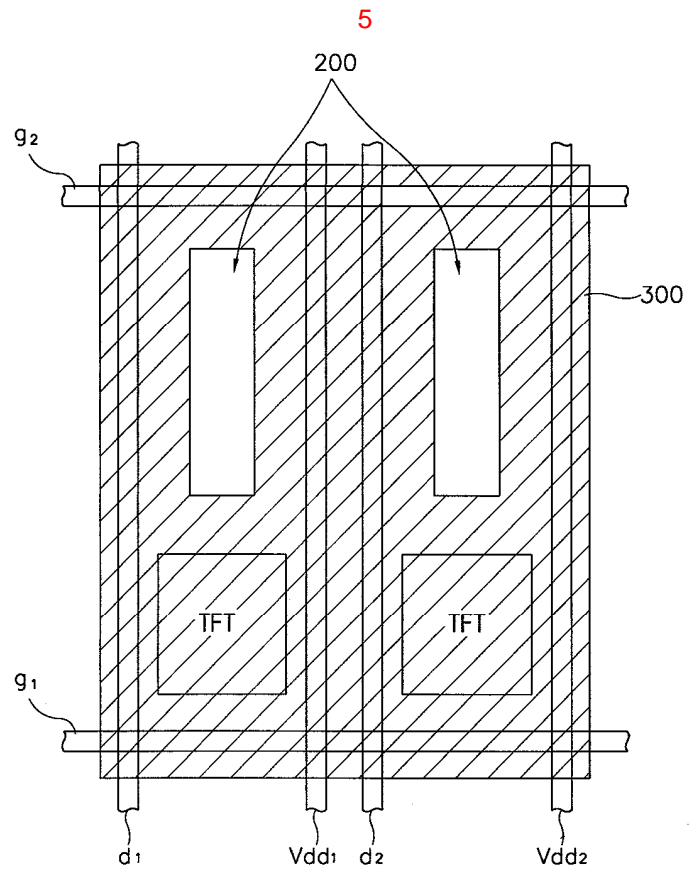












专利名称(译)	有源矩阵型有机电致发光显示装置及其制造方法		
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代理人(译)	PARK , YOUNG WOO		
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摘要(译)

公开了一种有源矩阵型有机电致发光显示装置及其制造方法。由低反射率材料构成的图案在除了配备有薄膜晶体管的基板上的像素电极，当前驱动的金属布线薄膜晶体管和连接到薄膜晶体管的像素电极的部分之外的区域中模制。形成薄膜晶体管和形成在像素电极上的有机电致发光层。最小化外部光从除了像素电极之外的区域反射，换句话说，可以实现非发光区域和高对比度。

